

IN THE CLAIMS:

Please amend claims 5, 10, 15 and 20, and add new claims 25-27 so that the claims read as follows:

1 (Original): A scintillator panel comprising a radiation-transparent substrate, a flat resin film formed on said substrate, a reflecting film formed on said flat resin film, and a scintillator formed on said reflecting film.

2 (Original): A scintillator panel according to claim 1, wherein at least a part of said scintillator is covered with a transparent organic film.

3 (Original): A scintillator panel according to claim 2, wherein said transparent organic film covers over the all surfaces of said scintillator.

4 (Original): A scintillator panel according to claim 1, wherein said flat resin film is directly formed on said substrate.

5 (Amended): A scintillator panel according to claim 1, wherein said scintillator is directly formed on said [flat resin] reflecting film.

6 (Original): A radiation image sensor comprising a radiation-transparent substrate, a flat resin film formed on said substrate, a reflecting film formed on said flat resin film, a scintillator formed on said reflecting film, and an imaging device disposed so as to face said scintillator.

7 (Original): A radiation image sensor according to claim 6, wherein at least a part of said scintillator is covered with a transparent organic film.

8 (Original): A radiation image sensor according to claim 7, wherein said transparent organic film covers over the all surfaces of said scintillator.

9 (Original): A radiation image sensor according to claim 6, wherein said flat resin film is directly formed on said substrate.

10 (Amended): A radiation image sensor according to claim 6, wherein said scintillator is directly formed on said [flat resin] reflecting film.

11 (Original): A method of making a scintillator panel comprising steps of:
forming a flat resin film on a radiation-transparent substrate;
forming a reflecting film on said flat resin film; and
forming a scintillator on said reflecting film.

12 (Original): A method of making a scintillator panel according to claim 11, further comprising a step of covering at least a part of said scintillator with a transparent organic film.

13 (Original): A method of making a scintillator panel according to claim 12, wherein said transparent organic film covers the all surfaces of said scintillator.

14 (Original): A method of making a scintillator panel according to claim 11, wherein said flat resin film is directly formed on said radiation-transparent substrate.

15 (Amended): A method of making a scintillator panel according to claim 11, wherein said scintillator is directly formed on said [flat resin] reflecting film

16 (Original): A method of making a radiation image sensor comprising steps of:
forming a flat resin film on a radiation-transparent substrate;
forming a reflecting film on said flat resin film;
forming a scintillator on said reflecting film; and
disposing an imaging device opposite said scintillator.

17 (Original): A method of making a radiation image sensor according to claim 16, further comprising a step of covering at least a part of said scintillator with a transparent organic film.

18 (Original): A method of making a radiation image sensor according to claim 17, wherein said transparent organic film is covering the all surfaces of said scintillator.

19 (Original): A method of making a radiation image sensor according to claim 16, wherein said flat resin film is directly formed on said radiation-transparent substrate.

20 (Amended): A method of making a radiation image sensor according to claim 16, wherein said scintillator is directly formed on said [flat resin] reflecting film.

21 (Original): A scintillator panel comprising a radiation-transparent substrate, a flat resin film formed on said substrate, a reflecting film formed on said flat resin film, and a scintillator formed on said reflecting film, wherein at least a part of said scintillator is covered with a transparent organic film, wherein said transparent organic film covers over all the surfaces of said scintillator, and wherein said transparent organic film reaches to the surfaces of said substrate.

22 (Original): A radiation image sensor comprising a radiation-transparent substrate, a flat resin film formed on said substrate, a reflecting film formed on said flat resin film, a scintillator formed on said reflecting film, and an imaging device disposed so as to face said scintillator, wherein at least a part of said scintillator is covered with a transparent organic film, wherein said transparent organic film covers over all the surfaces of said scintillator, and wherein said transparent organic film reaches to the surfaces of said substrate.

23 (Original): A method of making a scintillator panel comprising the steps of:

- forming a flat resin film on a radiation-transparent substrate;
- forming a reflecting film on said flat resin film;
- forming a scintillator on said reflecting film; and
- covering at least a part of said scintillator with a transparent organic film, such that said transparent organic film covers all the surfaces of said scintillator and reaches to the surfaces of said substrate.

24 (Original): A method of making a radiation image sensor comprising the steps of:

- forming a flat resin film on a radiation-transparent substrate;
- forming a reflecting film on said flat resin film;
- forming a scintillator on said reflecting film;
- disposing an imaging device opposite said scintillator; and
- covering at least a part of said scintillator with a transparent organic film, such that said transparent organic film is covering all the surfaces of said scintillator and reaches to the surfaces of said substrate.

25 (New): A scintillator panel comprising:
a radiation-transparent substrate;
a scintillator layer supported by said substrate;
a flat resin film; and
a reflecting film supported by said flat resin film, said flat resin film and said reflecting
film being provided between said radiation-transparent substrate and said scintillator layer.

26 (New) A scintillator panel according to claim 25, wherein said flat resin film is
directly formed on said substrate.

27 (New) A scintillator panel according to claim 25, wherein said scintillator is directly
formed on said reflecting film.